



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In the Patent Application of:

Mark W. Miles

Examiner: Barreca, Nicole

Serial No.: 10/074,562

Art Unit: 1756

Filed: February 12, 2002

For: METHOD FOR FABRICATING A STRUCTURE
FOR MICROELECTROMECHANICAL
SYSTEMS (MEMS) DEVICE

Mail Stop Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT UNDER 37 C.F.R. § 1.312(a)

Dear Sir:

As a Comment on Statement of Reasons For Allowance, Applicant respectfully requests the following amendments to claims 1, 12, 13, and 19 be made, strictly for clarification in light of the Examiner's Statement of Reasons For Allowance, or to correct typographical errors.

All allowed claims are listed below for the convenience of the Examiner.

IN THE CLAIMS:

1. (Currently Amended) A microfabrication process for fabricating a microelectromechanical systems device, comprising:

depositing one or a stack of layers on a substrate;

patterning said one or a stack of layers to form a plurality of longitudinally extending grooves grooves therein;

depositing a middle layer on said one or a stack of layers;

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